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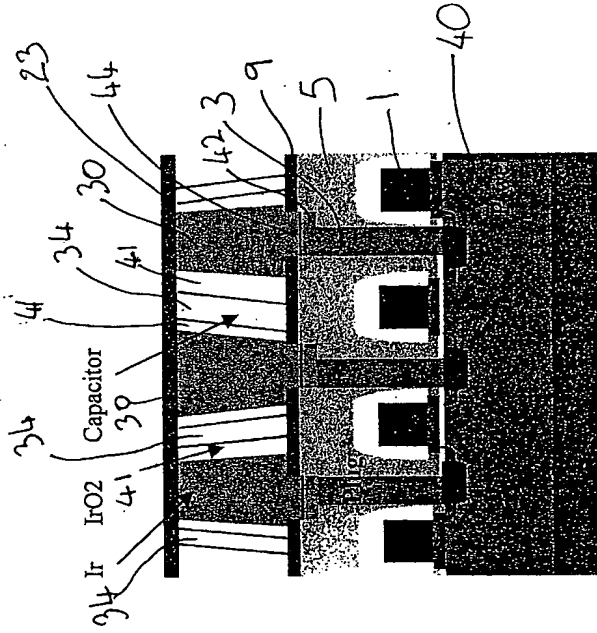


Fig. 2

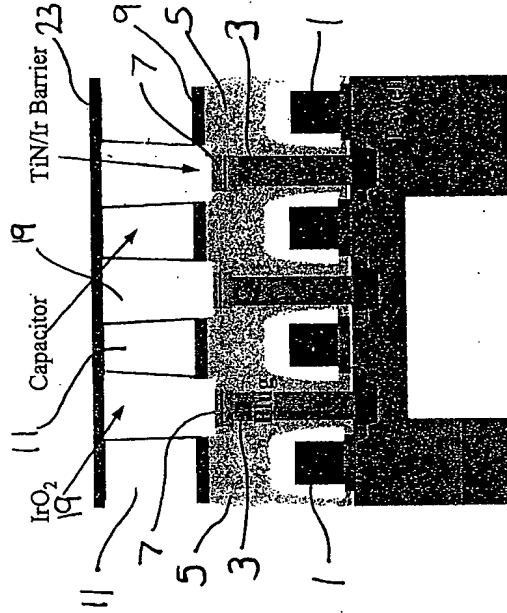


Fig. 1
[PRIOR ART]

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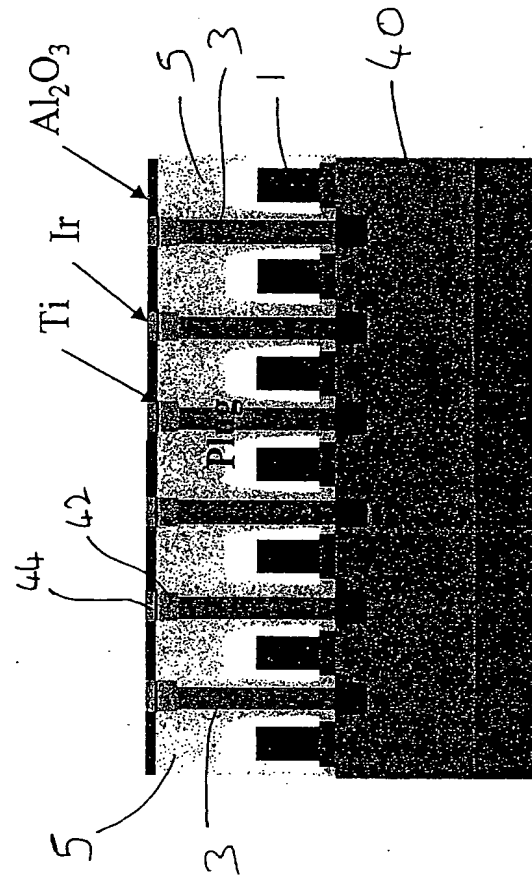


Fig. 3 Before Capacitor Process

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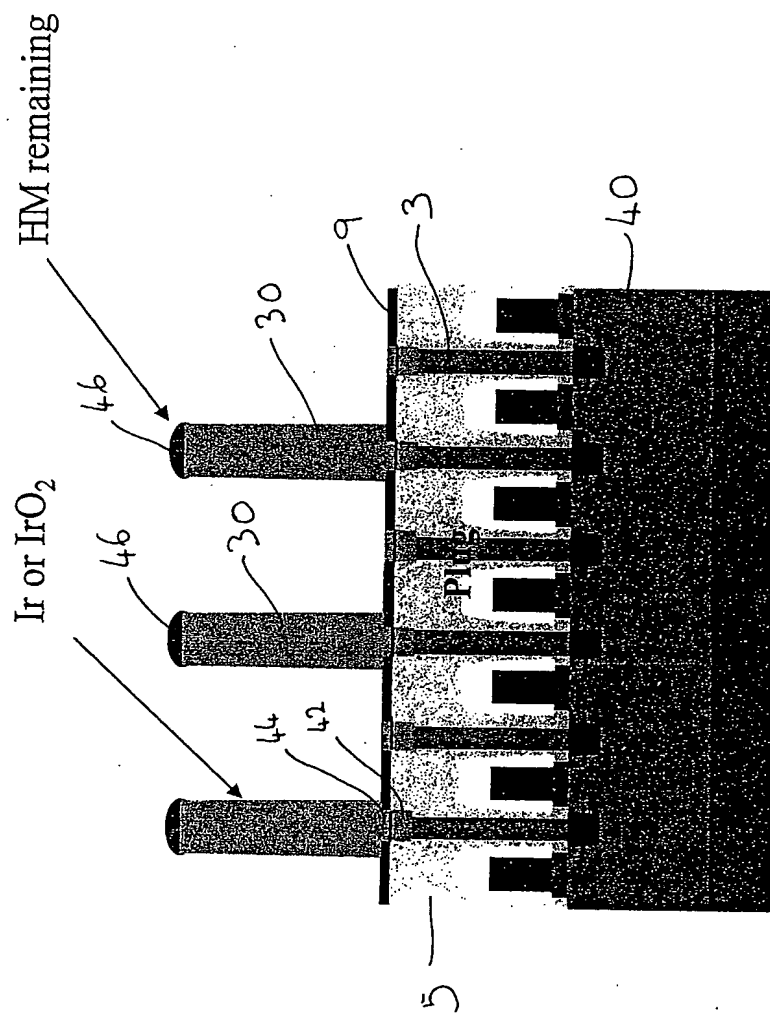


Fig. 4 Ir or IrO₂ Deposit and RIE

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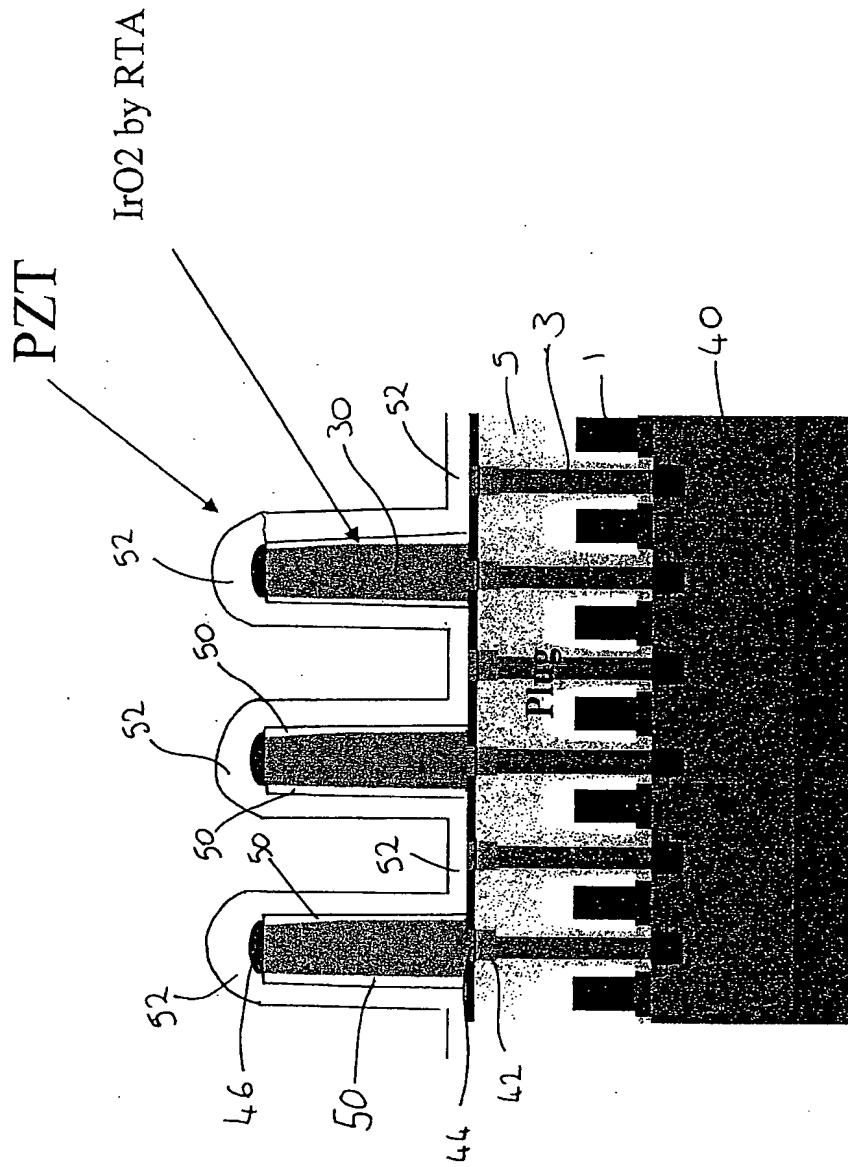


Fig 5 Making IrO2 on Ir surface
(by RTA, if electrode is IrO2, RTA is
not necessary)
and PZT Deposit on Surface

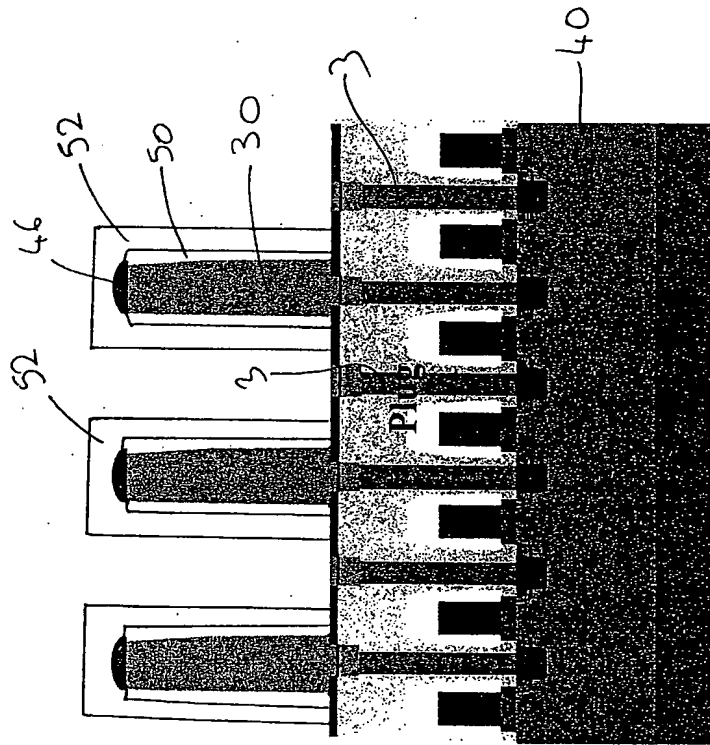


Fig. 6 PZT Etch Back

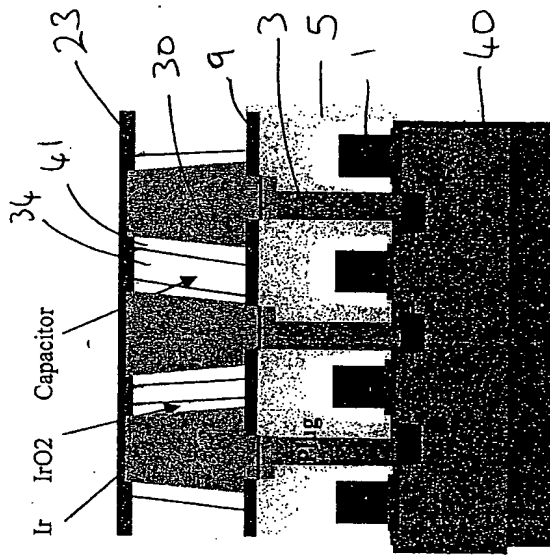


Fig. 7. Fill IrO₂ and Fill Ir (Or Only fill IrO₂)
CMP and then Al₂O₃ deposit